

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



1765

Applicant(s): Chih-Ming Ke

Application No.: 10/047,266 (CONF 4511)

Filed: 1/14/2002

Title: Reducing photoresist shrinkage via plasma treatment

Attorney Docket No.: 67,200-641

Group Art Unit:  
1765

Examiner:  
Kin Chan Chen

**RECEIVED**

Commissioner for Patents  
Alexandria, VA 22313-1450

OCT 08 2003

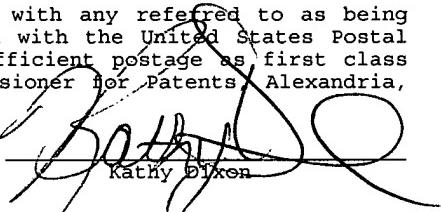
TC 1700

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I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Alexandria, VA 22313.

Date:

9-29-03

  
Kathy Dixon

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action of July 2, 2003, please amend this application as follows and consider the following remarks.